

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:
Panayotis C. Andricacos et al.

Application No.: 10/615,794

Confirmation No.: 3511

Filed: July 10, 2003

Art Unit: 1742

For: A VOID-FREE DAMASCENE COPPER
DEPOSITION PROCESS AND MEANS OF
MONITORING THEREOF

Examiner: N. A. Smith

REQUEST FOR RECONSIDERATION

MS AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

INTRODUCTORY COMMENTS

In response to the Office Action dated May 24, 2007, please consider the above-identified U.S. patent application as follows:

Remarks/Arguments begin on page 2 of this paper.